

Supplementary Material for

Near-infrared optical extinction of indium tin oxide structures prepared by nanosphere lithography

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Figure S1. AFM image of patterned ITO surfaces

Figure S2. SEM image of PMMA spheres for the NLS method

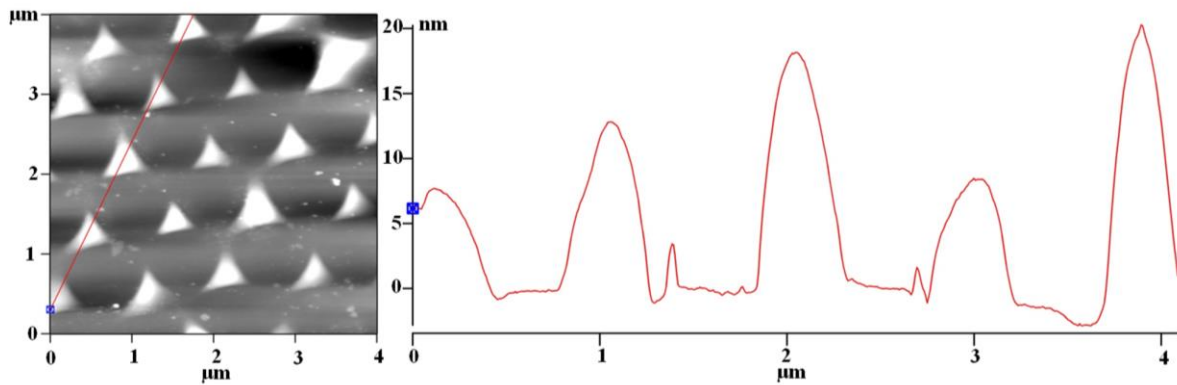


Figure S1. AFM image and height measurement of patterned ITO surfaces made using the nanosphere lithography method.

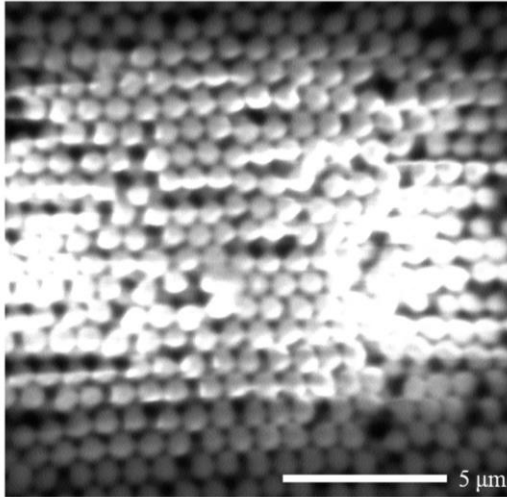


Figure S2. SEM image of PMMA spheres after spin coating. The diameters of the spheres are circa 700 nm to 800 nm. This is approximately 70 to 80 % of the original diameter. Multiple layers with PMMA were used in order to obtain a clear image of PMMA spheres. Since PMMA is not a conductive material, it is difficult to detect one or two layers in the SEM.